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	Application No.	Applicant(s)	- 4)
	10/017,262	ADLER ET AL.	
Notice of Allowability	Examiner	Art Unit	
	Phillip A. Johnston	2881	
The MAILING DATE of this communication and All claims being allowable, PROSECUTION ON THE MERITS herewith (or previously mailed), a Notice of Allowance (PTOLNOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT of the Office or upon petition by the applicant. See 37 CFR 1.	IS (OR REMAINS) CLOSED in t 85) or other appropriate commun RIGHTS. This application is su	this application. If not included ication will be mailed in due co	ourse. THIS
1. \boxtimes This communication is responsive to <u>amendment filed</u>	7 <u>-05-2005</u> .	,	
2. The allowed claim(s) is/are 69.			
3. \boxtimes The drawings filed on <u>14 December 2001</u> are accepted	by the Examiner.		
 4. ☐ Acknowledgment is made of a claim for foreign priority a) ☐ All b) ☐ Some* c) ☐ None of the: 1. ☐ Certified copies of the priority documents h 		(f).	
2. Certified copies of the priority documents h	• •		
3. Copies of the certified copies of the priority	documents have been received	in this national stage application	n from the
International Bureau (PCT Rule 17.2(a)). * Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DAT noted below. Failure to timely comply will result in ABANDO THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		a reply complying with the requ	irements
5. A SUBSTITUTE OATH OR DECLARATION must be su INFORMAL PATENT APPLICATION (PTO-152) which			TICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") r	must be submitted.		
(a) ☐ including changes required by the Notice of Draftsp	person's Patent Drawing Review	(PTO-948) attached	
1) 🗌 hereto or 2) 🗍 to Paper No./Mail Date			
(b) ☐ including changes required by the attached Examir Paper No./Mail Date	ner's Amendment / Comment or i	n the Office action of	
Identifying indicia such as the application number (see 37 CF each sheet. Replacement sheet(s) should be labeled as such			ack) of
7. DEPOSIT OF and/or INFORMATION about the deattached Examiner's comment regarding REQUIREMENT			te the
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. ☐ Notice of Info	ormal Patent Application (PTO-	152)
2. Notice of Draftperson's Patent Drawing Review (PTO-94			
3. Information Disclosure Statements (PTO-1449 or PTO/S Paper No./Mail Date		Mail Date <u>7-29-2005</u> . Imendment/Comment	
4. Examiner's Comment Regarding Requirement for Depos	sit 8. 🛛 Examiner's S	tatement of Reasons for Allow	ance
of Biological Material	9. 🗌 Other	•	

Examiners Amendment

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with James Okamoto on 7-26-2005. The changes made below are underlined.

The Claims are amended as follows;

- -- 69. A method of imaging a substrate, comprising:
- a) exposing said substrate to an influx of relatively high-energy electrons, said high-energy electrons having an energy selected to cause secondary electrons to leave said substrate,
- b) exposing said substrate to an influx of relatively low-energy electrons, said electrons having both an energy and a current density profile selected to maintain surface charge present on said substrate at a predetermined level,
- c) filtering said secondary electrons and the portion of said relatively lowenergy electrons which are reflected from the surface of said substrate, <u>after proper</u>
 <u>selection of the angle of incidence for the electron beams</u>, in order to select most or all
 of said secondary electrons which are emitted at angles other than perpendicular to
 the substrate and most or all of said reflected electrons which are scattered away from
 the specular angle, and to reject most or all of said secondary electrons which are

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emitted at an angle perpendicular to the substrate and most or all of said reflected electrons which are scattered at the specular angle.

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- d) focusing said selected secondary electrons and said selected reflected electrons to create an image of said substrate in the plane of a detector,
- e) detecting said selected secondary electrons and said selected reflected electrons, thereby imaging a portion of said substrate. --

Claims 1-68 are canceled.

Examiner's statement of reasons for allowance

The following is an examiner's statement of reasons for allowance:

2. Claim 69 is allowed because prior art fails to show the exposure of a substrate to both relatively low and high energy electron beams, while filtering the secondary electrons and the portion of the relatively low-energy electrons which are reflected from the surface of the substrate, after proper selection of the angle of incidence for the electron beams, in order to select most or all of the secondary electrons which are emitted at angles other than perpendicular to the substrate and most or all of the reflected electrons which are scattered away from the specular angle, and to reject most or all of the secondary electrons which are emitted at an angle perpendicular to the substrate and most or all of the reflected electrons which are scattered at the specular angle.

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

3. Any inquiry concerning this communication or earlier communications should be directed to Phillip Johnston whose telephone number is (571) 272-2475. The examiner can normally be reached on Monday-Friday from 7:30 am to 4:00 pm. If attempts to reach the examiner by telephone are unsuccessful, the examiners supervisor John Lee can be reached at (571) 272-2477. The fax phone number for the organization where the application or proceeding is assigned is 703 872 9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

PJ

July 29, 2005

SUPERVISORY PATENT EXAMINER
TECHNOLOGY CENTER 2800